

11/12C
**PATENT NUMBER and
ISSUE DATE**

U.S. UTILITY Patent Application

APPL NUM 10000458	FILING DATE 11/30/2001	CLASS 250	SUBCLASS U 512,22	GAU 2881	EXAMINER EL-SHAMMA
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**APPLICANTS: Yahiru Takehisa;

**CONTINUING DATA VERIFIED:

NONE UNK

** FOREIGN APPLICATIONS VERIFIED:

JAPAN 2001-033970 02/09/2001

JAPAN 2001-043195 02/20/2001

PG-PUB	DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>	
Foreign priority claimed 35 USC 119 conditions met		<input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> yes <input checked="" type="checkbox"/> no	ATTORNEY DOCKET NO 4641-61273
Verified and Acknowledged Examiner's initials: <i>YAH</i>			
TITLE : Methods and devices for evaluating beam blur in a charged-particle-beam microlithography apparatus			
U.S. DEPT. OF COMM./PAT & TM-PTO-430L (Rev. 12-94)			

NOTICE OF ALLOWANCE MAILED		Assistant Examiner	CLAIMS ALLOWED	
			Total Claims	Print Claim for O.G.
ISSUE FEE		DRAWING		
Amount Due	Date Paid	Sheets Drwg.		Figs.Drwg.
		Print Fig.		
		Primary Examiner		
		Application Examiner		
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE		
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